6/28/7 atent

UN 14 1999 IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

HI pmet 0 Q Freek 10/1/99

In feather application of:

LENZ

Application No. 09/105,547

Filed: June 26, 1998

For: FOCUS RING ARRANGEMENT

FOR SUBSTANTIALLY

ELIMINATING UNCONFINED

PLASMA IN A PLASMA PROCESSING CHAMBER

Atty. Dkt. No.: LAM1P089

Examiner: J. BETTENDORF

Art Unit: 2817

May 5, 1999

RECEIVED

JUN 2 1 1999

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner of Patents and Trademarks, Washington, DC 2023 Jon June 8, 1999.

Signed:

Sandra Halliwell

ASSISTANT COMMISSIONER FOR PATENTS Washington, D.C. 20231

AMENDMENT

Dear Sir:

In response to the Office Action mailed on April 14, 1999, please enter the following amendments and remarks:

In the Specification

Page 10, line 8, change "Teflon" to --TEFLON--;

Page 2, line 3, change "reactor top 102" to --reactor top 112--;

Page 2, line 18, change "RF power source" to --RF power source 120--;

In the Drawings

Amended Figures 1 and 2 have been provided with legends "Prior Art" as suggested by the Examiner. Reference to element 120 in Figure 1 has been added to the specification after "RF Power Source". Amended Figures 3 and 4 have been provided with reference